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**Amendments to the Claims:**

**Status of Claims:**

Claims 6, 34-38 are pending for examination after the present amendment.

Claims 1-5 and 7-33 were previously canceled.

Claims 6, 34, 38 are in independent form.

1-5. (Canceled).

6. (Currently Amended) A fluid ejecting device comprising:

a substrate having a feature formed by a first process that removes substrate material from the substrate, the feature extending into the substrate and within the substrate along an axis, where a cross-section of the feature taken transverse the axis has an upper terminus proximate a first substrate surface, the upper terminus having a first profile; and,

where the upper terminus is formed to have a second profile different from the first profile by a second different process that removes additional substrate material from the substrate and also removes debris created by the first substrate removal process and where the feature comprises a fluid-handling slot.

7-33. (Canceled).

34. (Currently Amended) A fluid-ejecting device comprising:

a substrate comprising at least a first substrate surface and a second substrate surface, a fluid-handling slot formed by at least two substrate removal processes and extending through the substrate between the first substrate surface and the second substrate surface, where the first substrate removal process comprises using a laser and the second substrate removal process comprises using abrasive particles; and,

an orifice layer positioned over the first substrate surface, the orifice layer having multiple firing nozzles formed therein, at least some of the nozzles being in fluid flowing relation with the fluid-handling slot, wherein at least one of the first substrate surface and the second substrate surface being ~~mechanically conditioned~~ processed by at least one of the removal

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processes prior to the orifice layer being positioned over the first substrate surface, at least in part, to reduce an incidence of debris occluding ink flow through individual nozzles.

35. (Currently Amended) The fluid-ejecting device of claim 34, wherein the fluid-handling slot is formed utilizing three ~~different~~ distinct substrate removal processes.

36. (Original) The fluid-ejecting device of claim 34, wherein the fluid-handling slot is formed utilizing at least one substrate removal process directed at the first substrate surface and at least two different substrate removal processes directed at the second substrate surface.

37. (Original) A print cartridge comprising, at least in part, the fluid-ejecting device of claim 34.

38. (Currently Amended) A micro electro mechanical systems device comprising:  
a substrate for supporting overlying layers; and,  
at least one feature formed in the substrate, the feature being formed with at least a first substrate removal process and a second different substrate removal process, wherein the second different substrate removal process also removes debris created by the first substrate removal process and wherein the first substrate removal process comprises using a laser beam and the second substrate removal process comprises directing abrasive particles toward the substrate.